

**IN THE CLAIMS**

1. (Canceled)

2. (Currently Amended) A method for treating perfluorocompounds, which comprises a step of decomposing perfluorocompounds contained in a gas, a step of bringing the discharged gas containing acid gases resulting from the decomposition of the perfluorocompounds into contact with one of water and an aqueous alkaline solution, thereby removing the acid gases from the discharged gas, a step of separating mists contained in the discharged gas by whirling of the discharged gas after the contact with one of the water and the aqueous alkaline solution, and a step of sucking the discharged gas separated from the mists by a jet stream of an injected gas, thereby ejecting the sucked gas.

3. (Currently Amended) A method according to Claim 1~~2~~, wherein the perfluorocompounds are catalytically decomposed.

4. (Currently Amended) A method according to Claim 1~~2~~, wherein the step of sucking the discharged gas by a jet stream of the injected gas, thereby ejecting the sucked gas is carried out by an ejector.

5. (Canceled)

6. (Currently Amended) A method for treating a discharged gas from a semiconductor production plant, which comprises a step of decomposing perfluorocompounds contained in a discharged gas from a semiconductor production plant, a step of bringing the discharged gas containing acid gases resulting from the decomposition of the perfluorocompounds into contact with one of water and an aqueous alkaline solution, thereby removing the acid gases from the discharged gas, a step of separating mists contained in the discharged gas by whirling of the discharged gas after the contact with one of the water and the aqueous alkaline solution, and a step of sucking the discharged gas separated from the mists by a jet stream of an injected gas, thereby ejecting the sucked discharged gas.

7. (Currently Amended) A method according to Claim 56, wherein the perfluorocompounds are catalytically decomposed.

8. (Currently Amended) A method according to Claim 56, wherein the discharged gas is sucked by the jet stream of the injected gas and ejected by an ejector.

9-16. (Canceled)

17. (New) A method for treating perfluorocompounds according to Claim 3, wherein the step of sucking the discharged gas separated from the mists by a jet stream of an injected gas, thereby ejecting the sucked gas, is performed by an ejector.

18. (New) A method for treating a discharged gas from a semiconductor production plant according to Claim 7, wherein the step of sucking the discharged gas separated from the mists by a jet stream of an injected gas, thereby ejecting the sucked gas, is performed by an ejector.